



# **Die Interconnection for Power Module 3.0**

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# **Needs for Interconnections**

Passives and actives components need "multi functional" interconnections :

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Electrical - Thermal – Mechanical (ETM)
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One, two or three functions associated to perform solutions for 3D integrated modules High performance is required for each physical domain and high reliability (critical)

# Several ways

- Conventional :
  - Brazing, bonding, sintering, electroplated via...  $\rightarrow$  not addressed here
- Non conventional :
  - Diffusion bonding, pressed nano post, pressed foam, electroplated via...

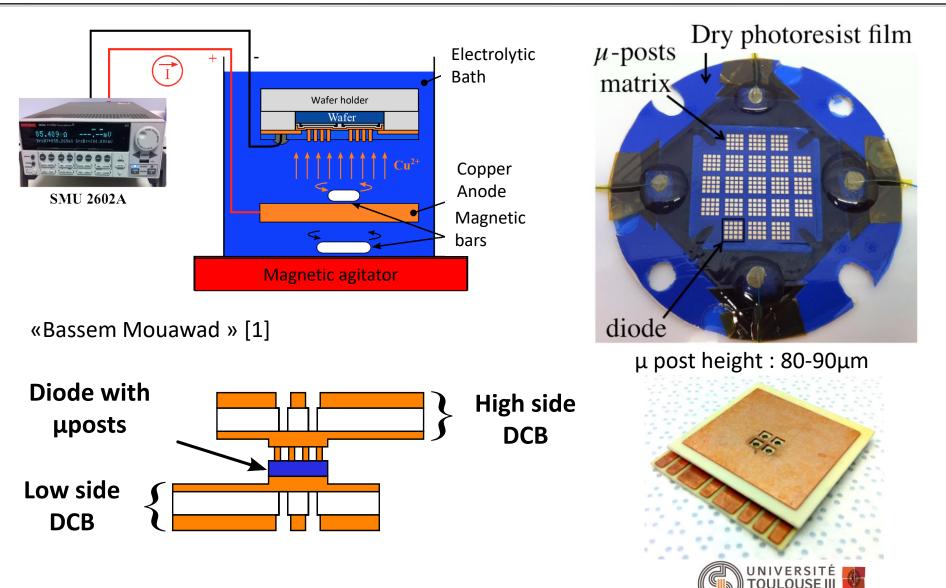




- Copper to copper "direct bonding"
- Copper nano post (ETM)
- Copper nano post in PCB environment (ET)
- Foams in PCB environment
- Conclusion

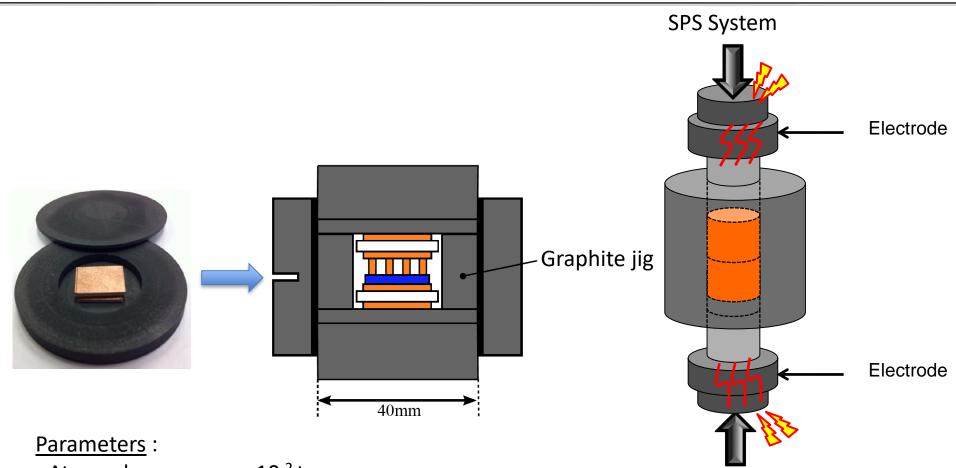


# Example "direct copper to copper bonding"



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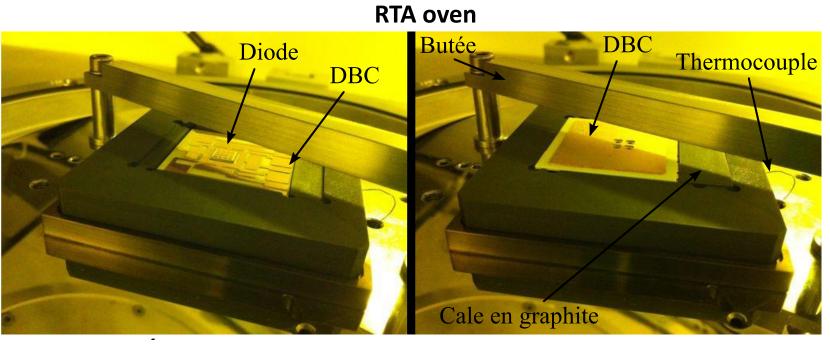
# Example "direct copper to copper bonding"



- Atmosphere vacuum 10<sup>-2</sup> torr
- Peak Temperature 200°C and 300°C (5min)
- Ramp 100°C.min<sup>-1</sup>
- Pressure few MPa (estimated)

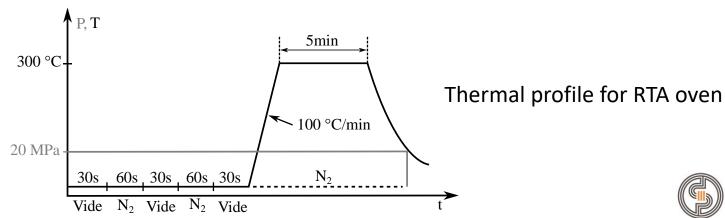


### Example "direct copper to copper bonding"





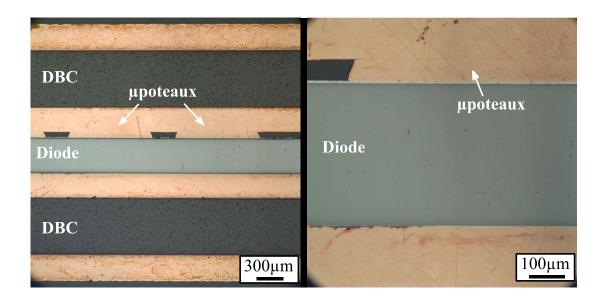






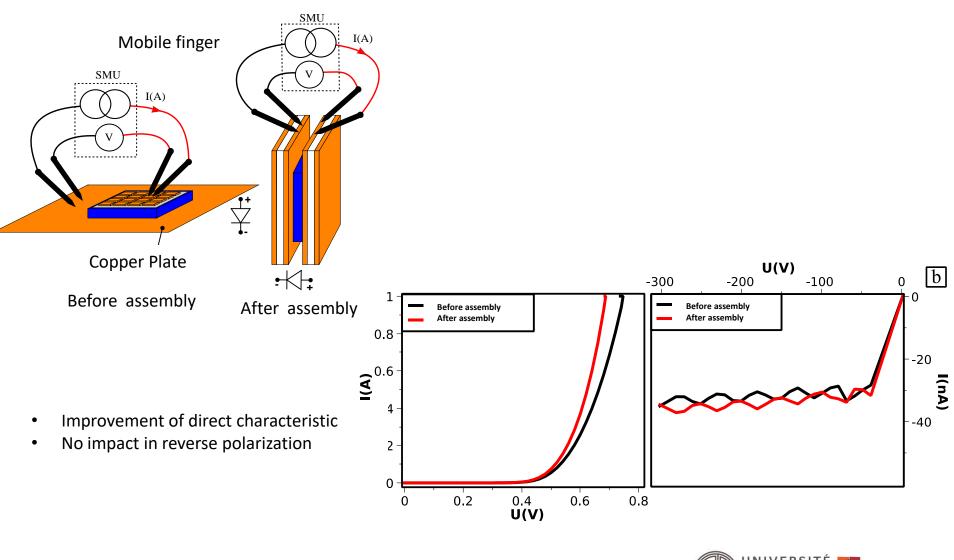
# Direct copper to copper bonding Mechanical Results

Mobile finger		SPS					RTA				
		N°	T (°C)	F (N)	$\frac{S}{(mm^2)}$	τ (MPa)	$\mathrm{N}^{\mathrm{o}}$	T (°C)	F (N)	$\frac{S}{(mm^2)}$	τ (MPa)
Force	Mechanical stop	1	300	113	2.63	43	1	300	199	11.8	16
		2	300	184	8.9	20	2	300	93	7.3	12
		3	300	275	8.4	32	3	200	133	5.2	25
		4	300	275	8.9	30	4	200	187	4	46
		5	200	181	7	25					
		6	200	21	1.1	18					
		7	200	31.5	5.6	5.6					
		8	200	176.5	8.4	21					
Suppo	ort tray										



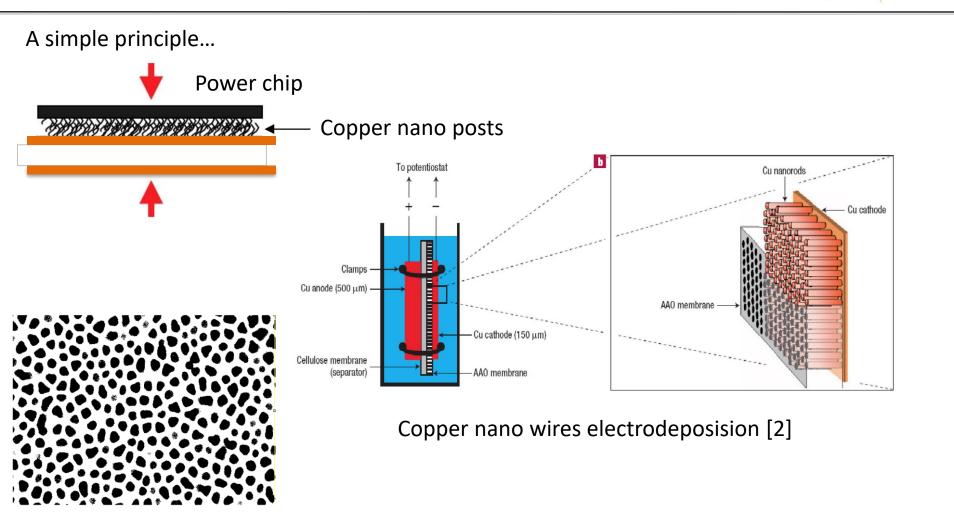


# Direct copper to copper bonding Electrical Results





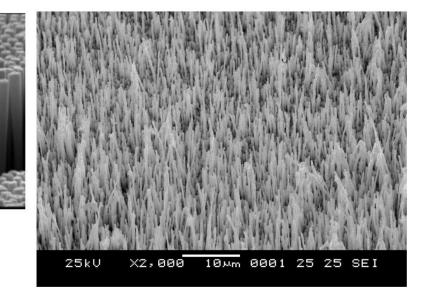
# Copper nano post $\rightarrow$ nano scratch



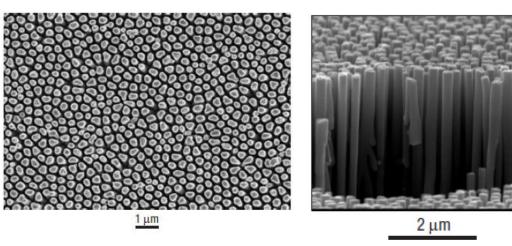
AAO : Anodic Aluminium oxyde membrane
Nanostructured matrix, 200nm pores, thickness 60µm
Around 1.10<sup>9</sup> pores / cm<sup>2</sup>

9

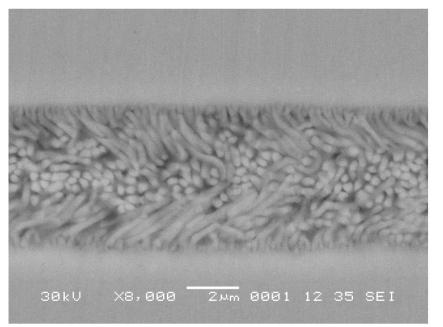
### Copper nano post assembly $\rightarrow$ Results



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Top view and side view of nano posts [3]



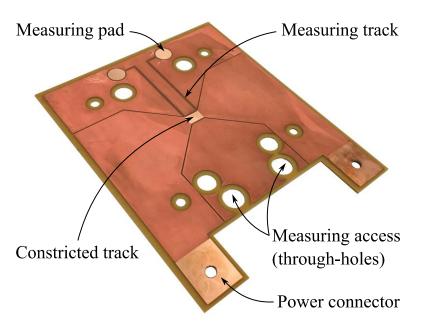
Top view of the nano posts [4]

- Acidic or alkaline electrodeposition bath
- Room temperature assembly
- High pressure applied up to 100MPa
- 60N/cm<sup>2</sup> pull test
- 80N/cm<sup>2</sup> shear test
- 10X the brazing resistance





#### A 0.8 mm high temperature core with two 105 $\mu$ m thick copper layers



PCB substrate with constricted area, its connectors and kelvin measuring tracks [5]

#### **Power connectors**

For electrical and thermal characterization

#### **Constricted** area

- Bare copper area for the interconnection manufacturing
- Constriction is done for helping thermal characterization

#### Measuring pads and tracks

Additional contacts for Kelvin measurements

#### **Measuring accesses**

To the opposite substrate measuring pads

Brown oxidized remainder copper and ground planes to increase prepreg adhesion





#### > Opened dry film on constricted area

- a. Dry film deposition ( $\approx$  45  $\mu$ m) on the whole PCB surface;
- b. Opening of the dry film over the constricted area.

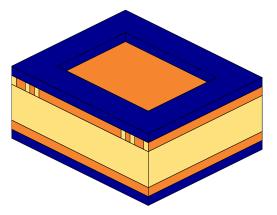


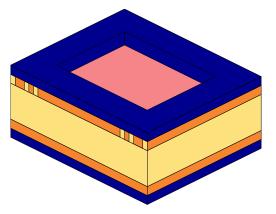
Figure 5: Manufacturing process of interconnection on the PCB substrate



Opened dry film on constricted area

#### Copper electro-etching on the constriction

a.  $\approx$  7 µm copper electro-etching (pulsed waveform) to increase adhesion of the surface.



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Figure 5: Manufacturing process of interconnection on the PCB substrate



Opened dry film on constricted area Copper electro-etching on the constriction

- Macro post electroplating (overflowing of dry film)
- a. ≈ 60 µm copper electroplating (pulsed waveform) The electroplating profile is adjusted to have the top of the post slightly higher than the dry film to ensure a complete filling of the cavity.

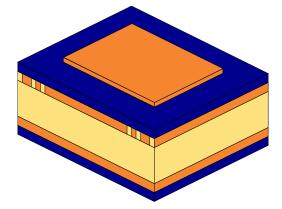


Figure 5: Manufacturing process of interconnection on the PCB substrate



Opened dry film on constricted area Copper electro-etching on the constriction Macro post electroplating (overflowing of dry film)

#### Leveling of the macro post by electro-etching

 a. ≈ 7 µm copper electro-etching (pulsed waveform) The copper post is etched to obtain a flushed surface between the dry film and the copper post. This is the condition to ensure a correct sealing for the forthcoming steps.

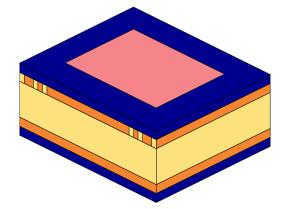


Figure 5: Manufacturing process of interconnection on the PCB substrate



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Opened dry film on constricted area Copper electro-etching on the constriction Macro post electroplating (overflowing of dry film) Leveling of the macro post by electro-etching

#### > Nano wires electroplating by pressed anode

- a. A nanoporous membrane is placed on top of the copper post;
- b. A solution of copper sulfate is spread over to act as an initiator;
- c. 2 layers of cellulosic papers are added on top as solution buffer;
- d. A copper anode is pressed on top of this assembly;
- Copper is electroplated during ≈ 1 hour through the membrane using a pulsed waveform.

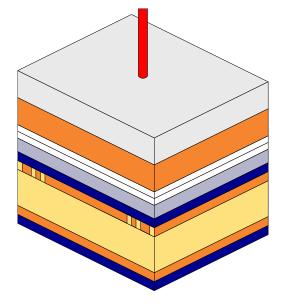


Figure 5: Manufacturing process of interconnection on the PCB substrate



Opened dry film on constricted area Copper electro-etching on the constriction Macro post electroplating (overflowing of dry film) Leveling of the macro post by electro-etching Nano wires electroplating by pressed anode

#### Membrane filling by distanced anode

Once the electrodeposition have been initiated

- a. The 2 layers of cellulosic papers are removed;
- b. The anode is placed further away;
- c. ≈ 6 hours copper electroplating is done until the membrane is filled.

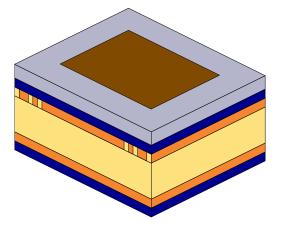
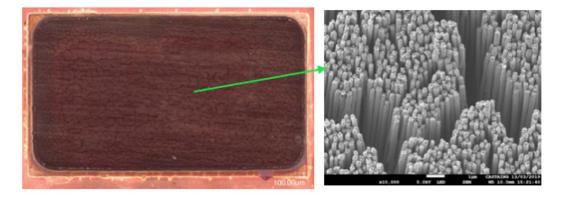


Figure 5: Manufacturing process of interconnection on the PCB substrate



Opened dry film on constricted area Copper electro-etching on the constriction Macro post electroplating (overflowing of dry film) Leveling of the macro post by electro-etching Nano wires electroplating by pressed anode Membrane filling by distanced anode

- Dry film and membrane removal
- a. Sodium hydroxide treatment at 45°C during half an hour.



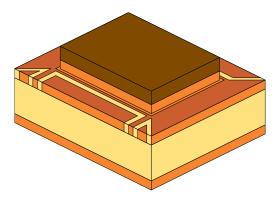


Figure 5: Manufacturing process of interconnection on the PCB substrate





# Assembly

#### **Proposed solution combines**

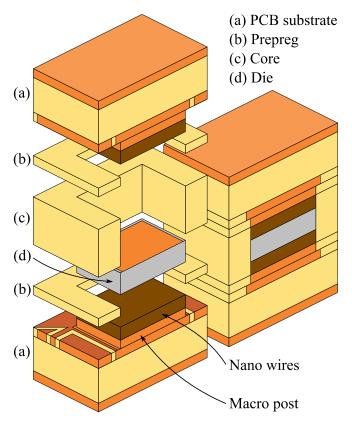
- PCB substrates (a)
- having a macro post and nano wires interconnection
- sandwiching a die (d) surrounded of core (c)
- assembled by thermo-compression of prepregs (b)

#### High level of integration

- 1. Double-side cooling possible (symmetrical structure)
- 2. Full copper and flexible interconnection
- 3. Expected resistant to cyclical stresses
- 4. Elementary block for power converter

Figure 3: Cross section schematic of the assembly with macro and nano structured interfaces

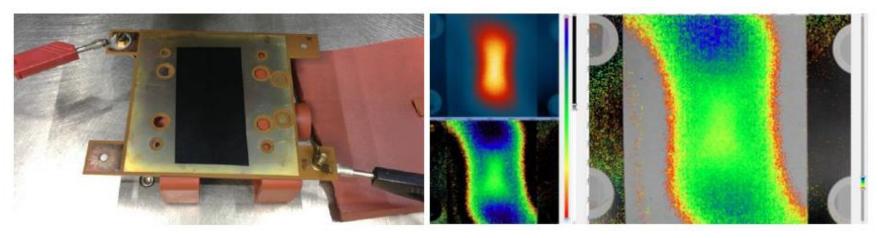






### **Perspectives**



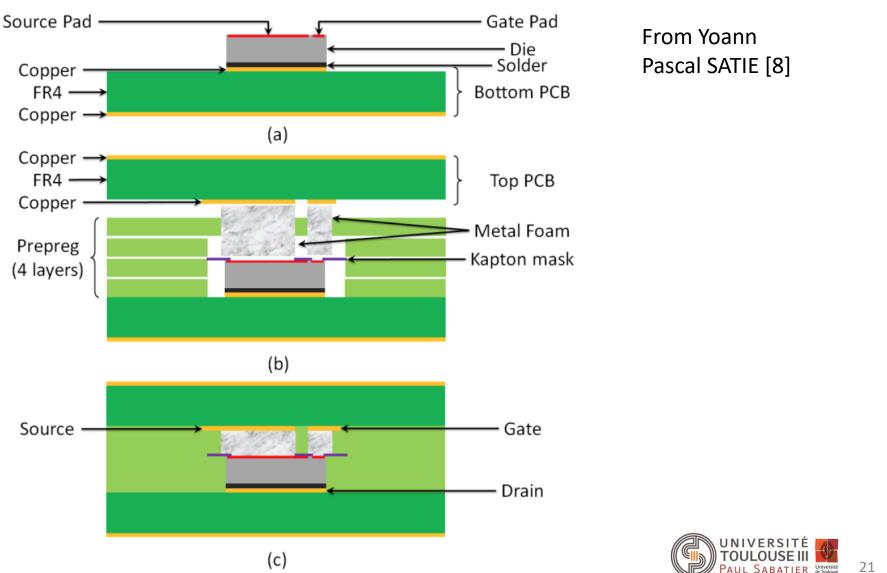


Lock-in thermography to detect hot spot inside PCB [6]

- Low specific resistance < 100µΩ.cm<sup>2</sup>
- Compatibility with PCB technology
- Electro Thermal functions
- Thermal characterization and reliability : test to do...



# Metal foam for contacts in PCB : Principle



Université

### Metal foam for contacts in PCB : Realization

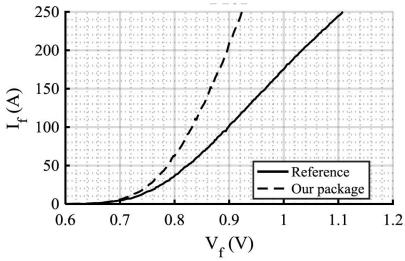


**Metallographic sections** 

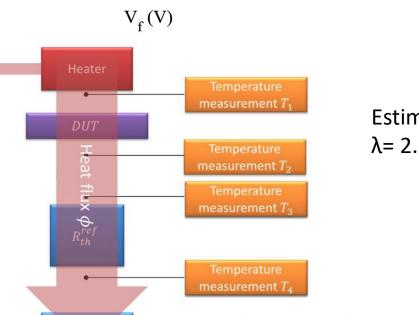


### Metal foam for contacts in PCB : Results

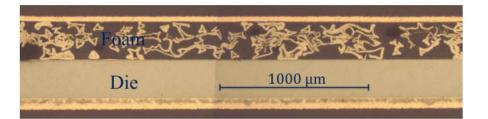




Ploss



Heatsink, Fan  $R_{th}(DUT) = \frac{T_1 - T_2}{\phi} = R_{th}^{ref} \cdot \frac{T_1 - T_2}{T_3 - T_4}$ 



Estimation of thermal conductivity :  $\lambda\text{=}~2.2~\text{Wm}^{\text{-1}}\text{K}^{\text{-1}}$ 



### Conclusions



- Many way to make interconnects...
- Direct bonding or pressed surface depends on environment (DBC, PCB)
- Only academic studies, many parameters to control final characteristics
- Compatible for 3D integration... but many tests to do...



# **Bibliography**

Laplace

[1] Bassem Mouawad PhD thesis « Assemblages innovants en électronique de puissance utilisant la technique de « Spark Plasma Sintering » 2013

[2] P. L. Taberna, et al., "High rate capabilities Fe3O4-based Cu nano-architectured electrodes for lithium-ion battery applications", Nature Materials, vol. vol. 5. pp. 567-573. ISSN 1476-1122, 2006.

[3] Quoc hung Luan PhD thesis Etude et mise en œuvre de techniques d'assemblages hybrides pour l'intégration tridimensionnelle en électronique de puissance, 2010.

[4] Etude et caractérisation d'une nouvelle connectique adaptée à l'intégration tridimensionnelle pour l'électronique de puissance, 2010.

[5] Bojan Djuric, Vincent Bley, Julien Morand, Olivier Dagut, Jean-Pascal Cambronne, Stefan Mollov Double Side Interconnection for Vertical Power Components Based on Macro and Nano Structured Copper Interfaces and Printed Circuit Board Technologies, MINAPAD 2019 May 22nd-23rd, Grenoble France.

[6] Morgane Mousnier PhD Thesis «Apport de la thermographie infrarouge à l'analyse de défaillance de composants et systemes electroniques ». 2019

[7] Yoann Pascal PhD thesis « Etude multicritère pour l'enfouissement partiel ou total de convertisseur d'électronique de puissance dans un circuit imprimé 2019.



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